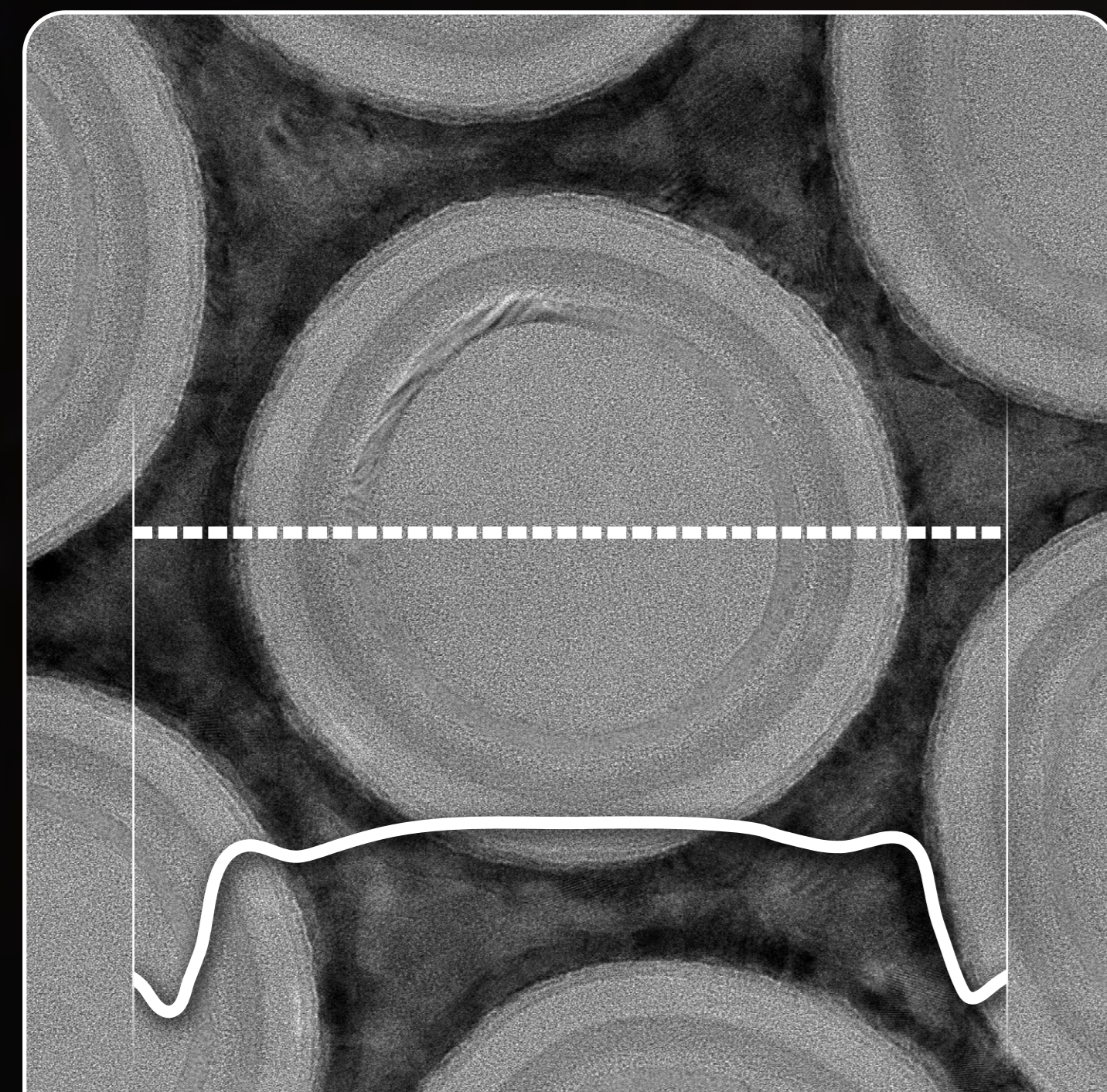


# Automated EFTEM metrology for advanced memory devices

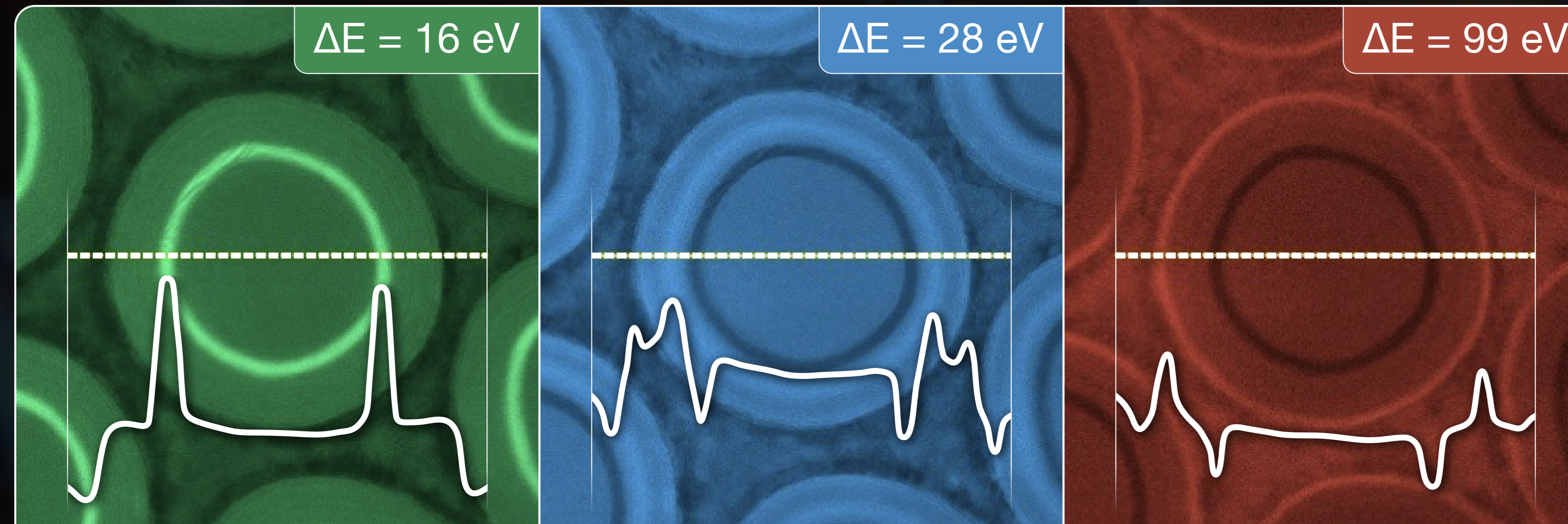
Accurate metrology of light-element semiconductor structures can be challenging with conventional TEM. The Thermo Scientific™ Metrios™ 6 (S)TEM helps address this with integrated EFTEM (energy-filtered TEM) automation, supporting improved contrast, measurement accuracy, and consistency for memory device characterization.

## Challenge



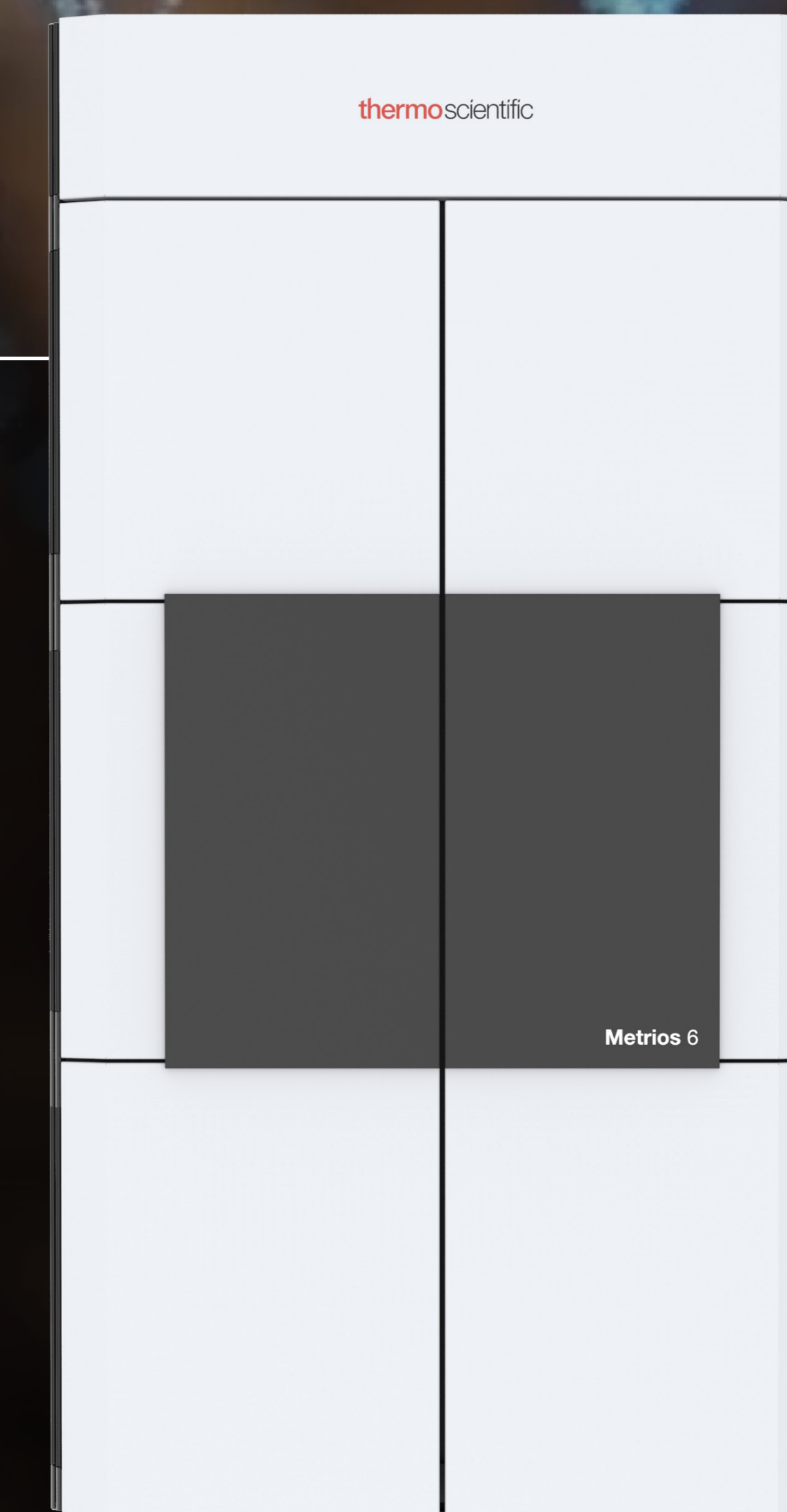
Low-contrast features in memory devices are difficult to measure accurately.

## Technology



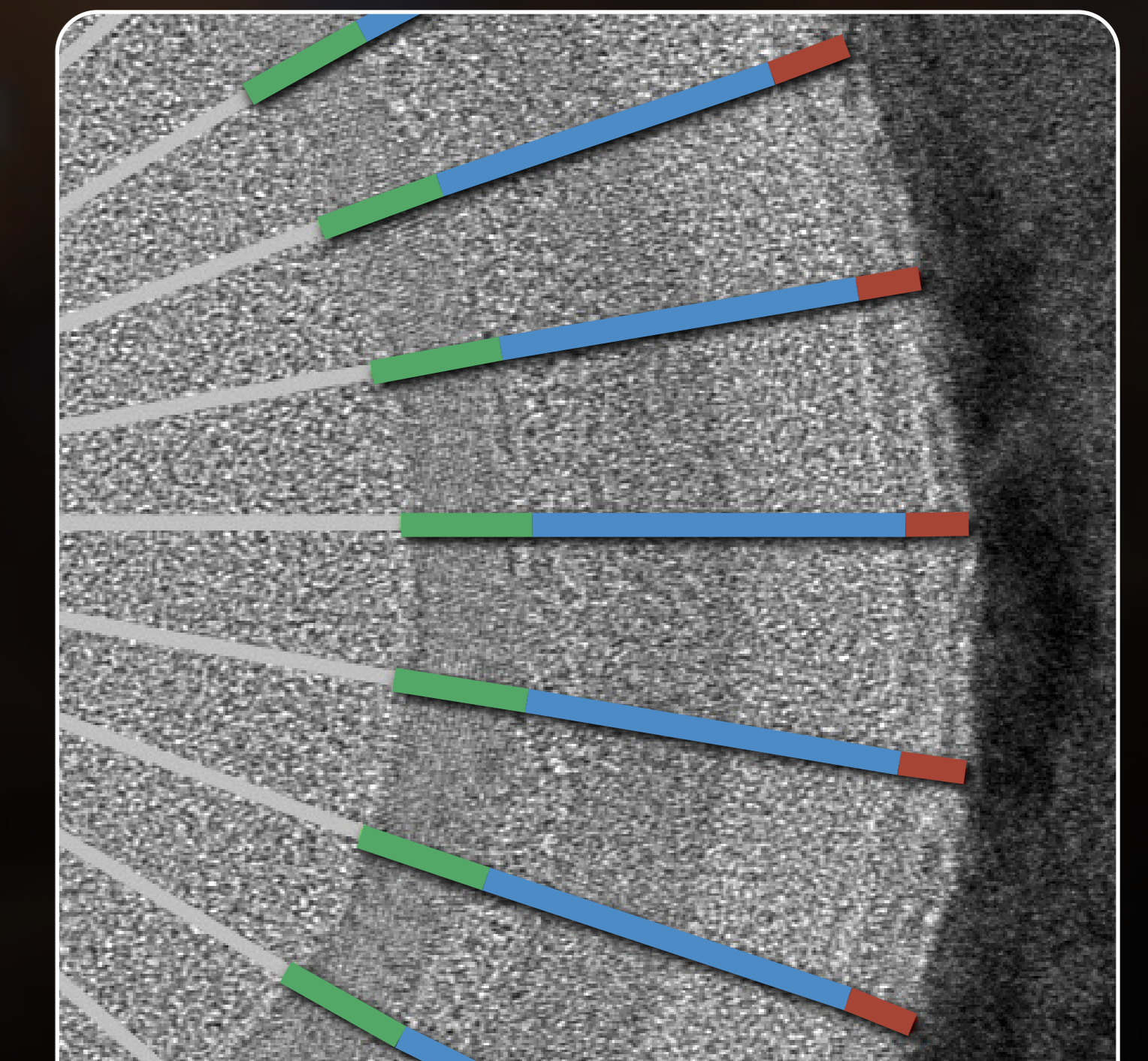
EFTEM enhances contrast by using electron energy loss signals to generate images.

## Integration



Automated workflows enable consistent image acquisition and analysis.

## Impact



Improved measurement accuracy and efficiency in metrology processes.

Learn more at [thermofisher.com/metrios6](https://thermofisher.com/metrios6)

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